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LIST OF ART-CITED BY APPLICANT  
(Use several sheets if necessary)

APPLICANT Garo J. Derderian

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June 11, 2001GROUP  
2818

## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
TZ	AA	2002/0064915A1	05/2002	Kitamura			
TZ	AB	2001/0023110A1	09/2001	Fukuzumi et al			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

TZ	AP		A.W. Ott, et al., "Atomic layer controlled deposition of Al <sub>2</sub> O <sub>3</sub> films using binary reaction sequence chemistry" Applied Surface Science (107) 1996, pps. 128-136.
	AQ		
	AR		

EXAMINER

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DATE CONSIDERED

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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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